EE505 MEMS Sensors and Actuators

Text: Foundations of MEMS
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Prerequisites:
EE409, EE414, or solid state physics

Course Outline
Microfabrication
  Lithography
  Etching
  Deposition
  Oxidation/Diffusion
Mechanical Transducers
  Basic Mechanics
  Capacitive Actuators
  Magnetic Actuators
  Thermal Actuators
Physical Sensors
  Strain
  Temperature
  Piezo
  Bimorph
  Inertial
Optical MEMS
RF MEMS
Bio-Chemical MEMS

Grading: one midterm, Literature Review Paper, Final exam, Final Lab Report